RESPONSE TO FINAL OFFICE ACTION Serial No. 10/628,001 Page 1 of 9

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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In re Application of: Davis, et al.

Case: AMAT/7938/ETCH/SILICON/JB

Serial No.: 10/628,001

Filed: **July 25, 2003** 

Examiner: Stevenson, Andre C.

Group Art Unit: 2812

Confirmation No.: 3943

Title: METHOD FOR AUTOMATIC **DETERMINATION OF** SEMICONDUCTOR PLASMA CHAMBER MATCHING AND SOURCE OF FAULT BY **COMPREHENSIVE PLASMA** MONITORING

Mail Stop AF Commissioner for Patents P.O. Box 1450

Alexandria, VA 22313-1450

SIR:

## RESPONSE TO FINAL OFFICE ACTION DATED FEBRUARY 10, 2006

In response to the Final Office Action dated February 10, 2006, having a shortened statutory period for response set to expire on May 10, 2006, and the Advisory Action dated June 26, 2006, please enter this response and reconsider the claims pending in the application for reasons discussed below. The Applicants have submitted payment for a one-month extension to reply using the Patent Electronic Business Center. Although Applicants believe that no other fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782 for any fees, including additional extension of time fees, required to make this response timely and acceptable to the Office.